

### **AMENDMENTS TO THE CLAIMS**

Please amend the claims as follows:

#### **Listing of Claims:**

Claim 1 (Currently Amended): A coating and developing system comprising:

a carrier station for loading a carrier containing a plurality of substrates from outside of the carrier station, and for unloading developed substrates that are contained in the carrier to the outside;

a processing block including a coating unit and a development unit, the coating unit for coating a surface of a substrate with a resist film, ~~a~~ the developing unit for processing the coated substrate processed by an immersion exposure process that forms a liquid film on the surface of the resist film for immersion exposure by a developing process using a developer;

an interface block including a substrate transfer part, an inspection unit, a control unit, and a drying unit, the interface block disposed adjacent to the processing block and connected to an exposure system for performing an immersion exposure process to a substrate, wherein the substrate transfer part receives the coated substrate from the processing block, sends the coated substrate to the exposure system, receives the exposed substrate from the exposure system, and sends the exposed substrate to the processing block, ~~an~~

the inspection unit including includes a substrate support device for supporting the exposed substrate and a liquid detector ~~capable of~~ for detecting at least a liquid used for forming the liquid film and adhering to the surface of the substrate supported by the substrate support device;

a ~~the~~ controller for ~~determining~~ determines whether or not the substrate needs to be processed by a drying process on the basis of a result of detection made by the liquid detector of the inspection unit; and

~~the~~ drying ~~means unit dries~~ ~~for drying~~ the substrate if the controller decides that the substrate needs to be processed by a drying process.

Claim 2 (Currently Amended): The coating and developing system according to claim 1, wherein

-the controller ~~has a function to send~~ sends a signal indicating an abnormal state to ~~an~~ the exposure system ~~processed the substrate by immersion exposure~~ when the result of detection made by the liquid detector indicates an abnormal state.

Claim 3 (Currently Amended): The coating and developing system according to claim 1, wherein

-the controller ~~has a function to determine~~ determines drying conditions for drying the substrate on the basis of the result of detection made by the liquid detector of the inspection unit, and to control drying operations of the drying ~~means~~ unit on the basis of the drying conditions.

Claim 4 (Currently Amended): The coating and developing system according to claim 1 wherein the interface block further comprising ~~comprises~~:

a heating unit for processing the exposed substrate by a heating process before the exposed substrate is subjected to a developing process; wherein the liquid adhering to the surface of the substrate is detected by the liquid detector of the inspection unit at least before the substrate is subjected to the drying process.

Claim 5 (Currently Amended): The coating and developing system according to claim 1 ~~further comprising~~, wherein: the interface block further includes:

a transport stage on which the exposed substrate is transferred from a substrate transfer means of the exposure system to the substrate transfer part of the interface block, wherein

the substrate support device of the inspection unit serves also as the transport stage  
~~processing block including the coating unit and the developing unit; and~~

~~an interface block disposed contiguously with the processing block and connected to an exposure system for processing the substrate by an immersion exposure process;~~

~~wherein the inspection unit and the drying means are included in the interface block.~~

Claim 6 (Currently Amended): The coating and developing system according to claim 5 ~~further comprising~~ wherein the substrate transfer part comprises:

a first substrate carrying device for carrying the substrate between the processing block and the interface block; and

a second carrying device for carrying the substrate between the interface block and the exposure system;

wherein the substrate support device of the inspection unit serves also as a transfer device on which the substrate is placed when the substrate is transferred between the first and the second carrying device.

Claim 7-10 (Cancelled).